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## Contents

### OPTICS ULTRA PRECISION MANUFACTURING AND TESTING

11568 02	Transformation of projection distortion for off-axis parabolic mirror in aberration-free point test
11000 02	[11568-2]
11568 03	Design of linear hyperchromatic lens in chromatic focal displacement sensor [11568-6]
11568 04	Large diameter optics support optimization based on finite element method and optical surface fitting with Zernike method [11568-7]
11568 05	Visual detection method for installation error of grating measurement system [11568-8]
11568 06	Research on technology of measuring and correcting the optical axis deviation of high-order aspheric lens [11568-9]
11568 07	Etching characteristics of crystal quartz by surface wave microwave induced plasma [11568-10]
11568 08	A method of transmission efficiency and uniformity measurement for optical fiber image transmission component [11568-12]
11568 09	A method for position and posture calculation of stamping parts by polarization vision [11568-13]
11568 0A	Research on the detection technology of aeroengine blade profile based on multi-axis compound measuring machine [11568-14]
11568 OB	Optical system design of continuous zoom objective lens with multi-conjugate distances [11568-15]
11568 0C	Research on visual guidance algorithm of forking robot based on monocular camera [11568-18]
11568 0D	Laser damage and evolution law of scratches on fused silica in etching [11568-19]
11568 OE	Design of low distortion MWIR optical system with high resolution and large width [11568-20]
11568 OF	Analysis of wear non-uniformity of pad in full aperture polishing [11568-21]
11568 0G	Laser beam shaping improves the transmission efficiency of Cassegrain antenna [11568-22]
11568 OH	Research on the calibration technology of three-dimensional laser scanner for measuring volume of railway tank car [11568-23]

11568 OI	Topological pupil segmentation and point spread function analysis for large aperture imaging systems [11568-24]
11568 OJ	A novel fiber grating preparation method: single-pulse laser for drawing tower gratings with the phase-mask technique [11568-25]
11568 OK	Measurement of nonlinear absorption of intense laser pulses by YVO4 crystal [11568-26]
11568 OL	Diamond turning of gap-masked lens array on curved substrate [11568-27]
11568 0M	On study of a method for detecting micro-deformation defects of steel plate surface [11568-28]
11568 ON	Computer controlled optical surfacing technology research of mid-spatial frequency errors on large-aperture planar optical components [11568-29]
11568 0O	Close-range industrial photogrammetry and application: review and outlook [11568-30]
11568 OP	High precision monoscopic fringe reflectometry based on a reference plane [11568-31]
11568 0Q	Development trend of aspheric test optical design [11568-33]
11568 OR	Research on machining path planning method for aspheric surfaces in two-dimensional ultrasonic elliptical vibration grinding [11568-34]
11568 OS	Design of dual channel optical system for compact airborne pods [11568-35]
11568 OT	Large-scale fast dwell time algorithm for complex structure phase optical elements based on magnetorheological polishing [11568-36]
11568 OU	Effect of excess surface charges on optical measurement of sub-micron particles with different properties [11568-37]
11568 0V	Analysis of the substrate temperature field for atmospheric pressure plasma jet processing [11568-38]
11568 OW	Calculation of verticality in large-aperture optical centering machinery turning [11568-39]
11568 0X	Reduction of effect of DOE's diffraction efficiency via optical-digital joint design [11568-40]
11568 0Y	Effect of annealing on properties of R <sub>2</sub> O-SiO <sub>2</sub> -B <sub>2</sub> O <sub>3</sub> glass [11568-41]
11568 OZ	Reactive ion figuring of large optical membrane components [11568-42]
11568 10	Simulation and polishing experiment of aspheric mirror with pre-filled surface figure [11568-43]
11568 11	Study on evolution law of optical surface roughness in Lap-MRF [11568-46]

11568 12	Distance measurement based on SD-OCT using multi-mode fiber probe for light delivery and collection [11568-48]
11568 13	Sub-aperture image stitching of cylindrical mirror surface defects based on dark-field imaging [11568-49]
11568 14	Investigation of dwell time based on Lucy-Richardson algorithm and Gercherg surface continuation algorithm [11568-50]
11568 15	Research on collision detection algorithm of multi-robot bonnet polishing system [11568-53]
11568 16	A method for measuring the width of welding seam based on machine vision [11568-54]
11568 17	The realization of USB3.0 auto focusing microscopic camera based on UVC protocol [11568-55]
11568 18	Quick-start HDMI microscope camera with dual operating system architecture based on Hi3559V200 platform [11568-56]
11568 19	Optimization of polishing wheel and investigation of its tool influence function [11568-57]
11568 1A	A method of gravity elimination in the testing process by using a highly lightweight mirror [11568-58]
11568 1B	Design of a double-telecentric optical system based on machine vision [11568-59]
11568 1C	Sub-aperture optical system testing by using of a modified simulateous fit method [11568-60]
11568 1D	Research and design of projection objective of automobile pixel headlight [11568-61]
11568 1E	Design and implementation of picture preview scheme in HDMI microscope camera [11568-63]
11568 1F	Flat-top and low-crosstalk CWDM with narrow straight directional couplers based on LN thin film [11568-64]
11568 1G	Large departure off-axis aspheric mirror testing with computer generated holograms and non-contact profile [11568-67]
11568 1H	Research on defect detection of the complex texture surface based on the multi-segment computational imaging technique [11568-68]
11568 11	Design of high-performance industrial camera system based on FPGA and DDR3 [11568-69]
11568 1J	Effect of fining agents on properties of R <sub>2</sub> O-SiO <sub>2</sub> -B <sub>2</sub> O <sub>3</sub> glass [11568-70]
11568 1K	Distribution characteristics of subsurface damage induced by different machining methods of fused silica [11568-71]
11568 1L	Modeling and simulation of dynamic errors in a coordinate measuring machine with 3-DOF laser interferometer [11568-72]

11568 1M	Research on multi-objective optimization of decision scheme in CNC manufacturing process [11568-73]
11568 1N	Design and analysis of micro-feed device for ultraprecision fly-cutting machine tool [11568-74]
11568 10	Study on the optimization of parameters in ultrasonic vibration turning of single crystal silicon [11568-75]
11568 1P	Research on photoelectric pulse monitoring system [11568-76]
11568 1Q	Study of the temporal phase-shifting interferometry measurement under the Tokamak related vibration environment [11568-78]
11568 1R	Control method of full index parameters for meter-level space aspheric mirror [11568-79]
11568 1S	Random variation effect on the fiber height caused by epoxy adhesive in optical fiber connectors [11568-80]
11568 1T	Research on wavefront metrology of continuous spiral phase plate based on phase retrieval [11568-81]
11568 1U	Theoretical study on the characteristics of sound field radiated by a Gaussian rectangular transducer [11568-82]
11568 1V	An investigation of data fusion for defects inspection in additive manufacturing [11568-83]
11568 1W	Local subaperture compensation and stitching interferometry [11568-84]
11568 1X	Theoretical study on the acoustic field characteristics of a rectangular transducer for ultrasonic testing [11568-85]
11568 1Y	Contact stiffness calculation of linear guide based on Bayesian theory [11568-88]
11568 1Z	Processing parameters optimization algorithm design and verification of suppress subsurface damage based on gradient algorithm [11568-89]
11568 20	Effects of mid-spatial frequency surface error on pupil characteristic parameters in lithography illumination system [11568-90]
11568 21	Nano precision non-contact complex differential confocal method to detect large concave aspheric surface [11568-91]
11568 22	Design on the photographic lamps for panoramic imaging [11568-92]
11568 23	3D shape measurement by a novel structured light encoding and decoding method [11568-93]
11568 24	Comparison of aspherical wavefront measurement by null compensator and computer- generated holograms [11568-94]

11568 25	Experimental study on rapid fabrication of a 316mm aperture free-form optical mirror [11568-101]
11568 26	Theoretical study on the acoustic field distribution of a rectangular transducer in attenuated media [11568-102]
11568 27	Formation of high-filling-factor microlens array on the posts [11568-103]
11568 28	Surface defects and their formation mechanism of optical fiber imaging elements [11568-139]